



Engineered Carbon Nanotube and Graphene for Sensors, Actuators and Nanoelectronics

Dr. E.H. Yang

Associate Professor, Department of Mechanical Engineering

Stevens Institute of Technology







I. Carbon Nanotube

- 1. Quantum Dots for RT SETs
- 2. Nanoactuator
- II. Graphene
 - 1. Electron Gyroscope
 - 2. Field Emission



Nanoelectronics Team

•



Dr. Frank Fisher
 Assistant Professor
 Department of
 Mechanical Engineering
 Stevens Institute of
 Technology



Dr. Stefan Strauf
Assistant Professor
Department of Physics
Stevens Institute of
Technology



 Dr. Daniel S. Choi Associate Professor Materials Science & Engineering McClure Hall 303C University of Idaho, Moscow



- Students
 - Kitu Kumar, Stevens (ME)
 - Yao-Tsan Tsai, Stevens (ME)
 - Nan Ai, Stevens (Physics)
 - Qiang Song, Stevens (Physics)
 - Erin Lynn Cochran, UI

MECHANICAL STEVENS INSTITUTE of TECHNOLOGY ENGINEERING Nanoactuator, E-Gyro, FE Teams Institute of Technology

 Dr. Seung Seob Lee Professor
 Department of Mechanical Engineering KAIST



Dr. Stefan Strauf
Assistant Professor
Department of Physics
Stevens Institute of
Technology



 Dr. Chris Search Assistant Professor
 Department of Physics Stevens Institute of Technology



- Postdocs/Students
 - Dr. Onejae Sul, Stevens (ME)
 - Dr. Seongjin Jang, Stevens (ME)
 - Kitu Kumar, Stevens (ME)
 - Dr. Seok Woo Lee, KAIST





- Air Force Office for Scientific Research (Award No. FA9550-08-1-0134)
- National Science Foundation (Major Research Instrumentation Program, Award No. DMI-0619762)
- US Army Armaments Research Development and Engineering Center
- Exchange student program by Brain Korea 21
- Stevens Startup funds







Stevens Micro Devices Laboratory



Gown room

Director: E. H. Yang Core faculty members: C.H. Choi, F. Fisher, S. Manoochehri, K. Pochiraju, and Y. Shi

- Initial funding provided by US Army/ARDEC
- Additional equipment funding:

FEVENS INSTITUTE of TECHNOLOGY

MECHANICAL

- AFM, thermal evapoartor (internal funding)
- NSF MRI: Nanomanipulator/SEM (awarded; PI Fisher)
- NSF MRI: ICP etcher (awarded; PI Shi)
- Stevens faculty, students, and researchers work collaboratively to develop novel devices in the areas of MEMS and nanotechnologies.





I-1. Carbon Nanotube: Quantum Dots



- Nanoelectronics: Working at the length scale of 1-100 nm, in order to create materials, devices and systems with fundamentally new properties and functions because of their nanoscale size.
 (www.nano.gov)
- Low dimensional materials such as Carbon Nanotube (CNT) and Graphene are considered strong candidates.
- Single Electron Device controls the movement of individual electrons; comprise quantum dot (QD) and tunnel junctions.





Why CNT SET?



$$E_{c} = \frac{e^{2}}{C_{\Sigma}} + \Delta E_{L} >> KT$$

- For practical room-temperature operation $(\sim 10kT = 259 \text{ meV})$, *d* should be ~1nm for Si.
- Core of the problem: Charge and island size fluctuation → The larger the island AND the larger the charging energy, the more effectively will spurious charges be suppressed.
- In CNT, confinement effects occur effectively at much large feature sizes (<30nm).





Henk W. Ch. Postma, et al. Science 293, 76 (2001);











 Near-term goal: CNT-based single electron transistor, stable up to room temperature by creating CNT quantum dots via a controlled growth followed by nanosegmentation process.



MECHANICAL STEVENS INSTITUTE of TECHNOLOGY ENGINEERING CNT-QD Fabrication Process Institute of Technology



- (b) CNT grown from the catalyst tip along the trench
- (c) CNT segmented by VAFM



Growth of In-Plane CNTs





- Substrate: 200 nm SIO₂/Si
- Growth conditions:

MECHANICA

of TECHNOLOGY ENGINEERING

- Pressure: 10 mTorr, Gas mixture: CH₄/Ar₂ (1:4)
- Temperature: 850°C, Growth time: 10 min









MECHANICAL

TEVENS INSTITUTE

ENGINEERING

 $V_{g}(V)$

CNTs with pronounced semiconducting behavior → 1st step towards exploiting CNT quantum dots with the goal to realize single electron device elements at room temperature.





CNT Segmentation



- Voltage-applied AFM (VAFM) process
 - Application of an electric field causes dissociation of the H_2O molecules into H+ and OH-.
 - Material can be either removed (volatile carbon oxide) or
 deposited (trapped oxygen in the carbon lattice) depending
 on process parameters:



Voltage input: -5 to -10V (100ms)

voltage, tip height, humidity, scan speed







Applied Voltage: -10 V Scan Speed: 0.05 μm/s













Scan Speed: 0.01 µm/s



Now and Future: Exploring OF TECHNOLOGY ENGINEERING Strong Confinement Region



Create ~10nm CNT-QDs with <5nm tunnel barriers

MECHANICAL

- (For semiconducting CNTs), the band gap. plays a strong role in the transport current.
- Perform a systematic study to understand ۲ the single electron transport and storage properties \rightarrow Differential conductance measurements and scanning probe spectroscopy under optical excitation.



Low-temperature (4-300K) vacuum setup Strauf, Stevens (Physics)



I-2: CNT Nanoactuator

- Bimorph: piezoelectric, magnetic, thermal (optical, RF....)
- Low thermal expansion compared to metals:
 - $\alpha_{CNT} = < 3x10^{-6} / K$
 - $\alpha_{AI} = 23 \times 10^{-6} / K$

MECHANICAL

TEVENS INSTITUTE of TECHNOLOGY ENGINEERING

- Vertical nanoactuator arrays
 - ➔ Individual nanoactuator



Falvo M. et al, "Mechanics and friction at nanometer scale", Journal of nanoparticle research, Vol. 2, p237

STEVENS

Institute of Technology





Choi C. H. et al, Biomaterials, Vol. 28, p1672 (2006)



MWNT-Al Bimorph?





Thermally evaporated AI films

200°C (x = y = and x = y) 30°C (x = y = and x = y) (x = y = and x =

Actuation inside an SEM chamber

- Thermal evaporation on MWNT at RT and 150 K.
- Metal grains in various morphology
- Inconsistent deflection behaviors: do not follow the prediction well.



MWNT-Al Bimorph PLD



Pulsed Laser Deposition (PLD)



- Deposition Rate: 0.6 Å per min @ 160 mJ/pulse in 10 Hz
- Precisely formed metal film on only one side of a MWNT







$$\Delta = \frac{3L^{2}(\alpha_{Al} - \alpha_{MWNT})\Delta T(d_{Al} - d_{MWNT})}{d_{Al}d_{MWNT}} \left[\left(\frac{d_{Al}}{d_{MWNT}} \right)^{2} \frac{Y_{Al}}{Y_{MWNT}} + 4 \frac{d_{Al}}{d_{MWNT}} + 6 + \left(\frac{d_{MWNT}}{d_{Al}} \right)^{2} \frac{Y_{MWNT}}{Y_{Al}} + 4 \frac{d_{MWNT}}{d_{Al}} \right]^{-1} \frac{1}{2} \frac{1}{2} \frac{Y_{MWNT}}{Y_{Al}} + 4 \frac{1}{2} \frac{1}{2}$$

• From calculation, Δ = 430 nm.

MECHANICAL

TEVENS INSTITUTE of TECHNOLOGY ENGINEERING

• Measurement, Δ = 500 ± 200 nm at Δ T ~100K.



LFM Measurement







Force Measurement





O. Sul ad E. H. Yang, "A Multi-Walled Carbon Nanotube-Aluminum Bimorph Nanoactuator," Nanotechnology, vol. 20, 095502, 2009.









MWNT used

- L = 2.0 \pm 0.2 μm long
- ϕ = 200 ± 20 nm

Measured force up to 1 $\mu\text{N}.$

$$F = \frac{w(\alpha_{Al} - \alpha_{MWNT})\Delta T}{L} \frac{Y_{Al}Y_{MWNT}d_{Al}d_{MWNT}(d_{Al} + d_{MWNT})}{d_{Al}Y_{Al} + d_{MWNT}Y_{MWNT}}$$

MECHANICAL STEVENS INSTITUTE of TECHNOLOGY ENGINEERING NI-Al₂O₃ Bimorph Actuation STEVENS Institute of Technology



O. Sul, S. Jang and **E. H. Yang**, "Fabrication and Characterization of a Ni-Al₂O₃ Bimorph Nanoactuator", *Journal of Vacuum Science and Technology B; in review*





On-demand control of surface features → wetting behaviors (Example: Change in water contact angle)





+ Nanoantenna?

On-demand control of surface features → cell behaviors (Example: Adhesion, cell morphology, surface antigen display, gene expression...)

II-1: Graphene Gyroscope? STEVENS Institute of Technology



MECHANICAL

of TECHNOLOGY ENGINEERING

Graphene is a single-atom-thick planar 2-D layer of carbon atoms in a honey-combed lattice composed of two superposed triangular sublattices with superior electronic properties.

- Conduction and valence bands touch at two nodal zero-gap points in the first Brillouin zone.
- Electron mobility as high as 200,000 cm²/Vs at RT, with carrier density of 10¹³/cm² and mean free path ~ 1 μm.
- Stable up to 3,000 K and has a quantum hall effect at RT.

Matter Wave Gyroscopes? STEVENS Institute of Technology



MECHANICA

TECHNOLOGY ENGINEERING

- Sensitivity: 60 µdegree/hr bias stability
- Operation at ~100nK, high vacuum, high magnetic fields

•

Very heavy: several hundred kilograms

Rotational motion can be detected via a phase shift between two arms of an interferometer.



Optical gyroscopes

- No moving parts
- 0.01 degree/hr bias stability
- Costs > \$ 250K
- 50 cm3, 19 lb, 30W





Electron Interferometer



- Electron interferometer: Only experiments were done with electron beam in vacuum.
- Using electron Sagnac effect, the measured signal would be larger than an optical interferometer by, $Mc^2 / \hbar \omega \sim 10^5$



Concept and calculation by Prof. Search, Stevens (Physics)

M. Zivkovic, M. Jaaskelainen, C. P. Search, and I. Djuric, "Sagnac Rotational Phase Shifts in a Mesoscopic Electron Interferometer with Spin-Orbit Interactions," PACS, February 1, 2008





Graphene Ring Design



- Solid-state electron interferometer
- Electron scattering lengths
- Sagnac phase shift proportional to both the enclosed area of the interferometer and the rotation rate.
- Cascaded linear array enhances the sensitivity by N^{1/2}.



by Prof. Search, Stevens (Physics)

M. Zivkovic, M. Jaaskelainen, C. P. Search, and I. Djuric., Phys. Rev. B **77**, 115306 (2008)





Graphene Synthesis







Nanopatterning (VAFM)





K. Kumar, Y. T. Tsai, O. Sul and **E. H. Yang**, "Nanoscale Graphene and Carbon Nanotube Lithography using an Atomic Force Microscope," *ASME International Mechanical Engineering Congress and Exposition*, Lake Buena Vista, FL, Nov 2009



Performance Testing



• The electron wave interference changes the conductance across the rings.

Phase shift depends on rotation rate $\Delta \phi = 2mA\Omega/\hbar$ Conductance depends on phase shift $G = I/V = (e^2/h)\cos^2(\Delta \phi + \theta)$



- Modulation of the path length using a gate electrode close to one arm to simulate the *rotation* (interferometer detuning)
- The fully developed device with thousands times smaller area of graphene would measure equivalent rotations as optical gyroscopes.







- CNT's field emission properties: turn-on voltage 1~3 V/ μ m and emission current as high as 100 μ A from a single CNT
 - attractive as cold-cathode field emission sources and lightweight packages
- FE characteristics from graphene?
- Planar form of graphene → CMOS compatible process, an advantage for potential industrial fabrication



Previous Study on Graphene Filed Emission



- Randomly oriented oxidized graphene sheets protruding from the film: *Applied Physics Letters* 93, 233502 2008
- There is no report on the field emission
 - from high-quality (highly ordered pyrolyzed) graphene sheets ,
 - in planar geometry, or
 - in device applications.





Experimental Setup









Graphene Prepared for Field Emission Testing





One tip placed on the sample directly as a cathode and the other placed apart from the edge of graphene sheet as an anode.









- Electron emission current exponentially increased up to 170 nA following the behavior of the Fowler-Nordheim relationship.
- For the exponentially increasing region (of current), the F-N curve shows linear relationship (confirming the field emission characteristic).



S. W. Lee, S. S. Lee and **E. H. Yang**, "Field Emission from Graphene Structures for Vacuum Transistor Applications," ASME International Mechanical Engineering Congress and Exposition, Lake Buena Vista, FL, Nov 2009



- Crystal orientation, number of layers, suspended structures...
- A graphene electrodes (source, drain, gate....) can be fabricated inplane along with other components (e.g. precisely patterned graphene triode based on high-quality graphene sheets)



EH Yang, Stevens Institute of Technology





- We are exploiting carbon nanotube and graphene nanostructures.
- Overcoming the technical challenges will enable one to leverage the outstanding properties of CNT and graphene in the development of next-generation devices with unrivaled functionality.
- Such capabilities show potential widespread application in areas such as sensors, actuators and nanoelectronc systems.



Project Overview









Large-stroke deformable mirror



